

In the claims:

Please substitute the following full listing of claims for the claims as originally filed or most recently amended.

1. (Currently amended) A method of adjusting carrier mobility for different semiconductor conductivities on the same chip comprising steps, in sequence, of:
~~providing~~ forming a first layer of material ~~providing~~ applying a first stress level on a portion of a surface of a chip,
selectively reducing said first stress level of a portion of said first layer of material,
~~providing~~ forming a second layer of material ~~providing~~ applying a second stress level on a portion of a surface of the chip said second stress level being different from said first stress level, and
selectively reducing said second stress level of a portion of said second layer of material.
2. (Currently amended) The method as recited in claim 1, wherein said first stress level is tensile and said second stress level is compressive.
3. (Original) The method as recited in claim 1, wherein said step of providing a first layer is performed by plasma enhanced chemical vapor deposition.
4. (Original) The method as recited in claim 3, wherein said first stress level is developed in accordance with plasma power during said plasma enhanced chemical vapor deposition.
5. (Original) The method as recited in claim 1, wherein said step of providing said second layer is performed by thermal chemical vapor deposition.
6. (Original) The method as recited in claim 5, wherein said step of providing a first layer is performed by plasma enhanced chemical vapor deposition.

7. (Original) The method as recited in claim 6, wherein said first stress level is developed in accordance with plasma power during said plasma enhanced chemical vapor deposition.

8. (Original) The method as recited in claim 1, wherein one of said first layer of material and said second layer of material is silicon nitride or silicon oxynitride.

9. (Currently amended) The method as recited in claim 1, including the further step of:
forming two transistors in said portion of a surface of a chip prior to said steps of
providing said first and second layers of material.

10. (Original) The method as recited in claim 1, wherein said step of providing a second layer of material results in a greater thickness than a thickness resulting for said step of providing a first layer of material.

11. (Currently Amended) The method as recited in claim 1, wherein said steps of reducing stress are performed by implanting ions of germanium, arsenic, xenon, indium, antimony, silicon, nitrogen, oxygen or carbon.

12-20. (Withdrawn)